Design and Performance Study of High Efficiency/Low Efficiency Roll-off/High CRI Hybrid WOLEDs Based on Aggregation-Induced Emission Materials as Fluorescent Emitters

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1. EL spectra of monochromatic devices



Figure S1. EL spectra of TPB-AC, CP-BP-PXZ, and Ir(dmppr-mp)₂(divm) based monochromatic devices.

2. Current efficiency-luminance characteristics of devices W1, W2, and W3



Figure S2. Current efficiency–luminance characteristic of device W1 with the configuration of ITO/HAT-CN (5 nm)/TAPC (50 nm)/TCTA (5 nm)/TCTA: 3 wt% Ir(dmppr-mp)₂(divm) (8 nm)/CP-BP-PXZ (8 nm)/TPB-AC (10 nm)/TmPyPB (40 nm)/LiF (1 nm)/Al (120 nm). Inset: the structure of emitting layer in device W1.



Figure S3. Current efficiency–luminance characteristic of device W2 with the configuration of ITO/HAT-CN (5 nm)/TAPC (50 nm)/TCTA (5 nm)/TCTA: 3 wt% Ir(dmppr-mp)₂(divm) (8 nm)/CP-BP-PXZ (7 nm)/TCTA (2 nm)/TPB-AC (10 nm)/TmPyPB (40 nm)/LiF (1 nm)/Al (120 nm). Inset: the structure of emitting layer in device W2.



Figure S4. Current efficiency–luminance characteristic of device W3 with the configuration of ITO/HAT-CN (5 nm)/TAPC (50 nm)/TCTA (5 nm)/TCTA: 3 wt% Ir(dmppr-mp)₂(divm) (5 nm)/CP-BP-PXZ (10 nm)/TCTA (3 nm)/TPB-AC (10

nm)/TmPyPB (40 nm)/LiF (1 nm)/Al (120 nm). Inset: the structure of emitting layer in device W3.



3. EL spectra of devices C1-C3, and W2

Figure S5. EL spectra of devices C1-C3, and W2 measured at 4 V. Device structure is ITO/HAT-CN (5 nm)/TAPC (50 nm)/TCTA (5 nm)/TCTA: y wt% Ir(dmppr-mp)₂(divm) (8 nm)/CP-BP-PXZ (7 nm)/TCTA (2 nm)/TPB-AC (10 nm)/TmPyPB (40 nm)/LiF (1 nm)/Al (120 nm), where y = 0 for device C1, y = 1 for device C2, y = 2 for device C3, y = 3 for device W2.

4. PL spectra of film 1-4



Figure S6. PL spectra of films 1-4. Structures of film 1: substrate/TCTA (8 nm)/CP-BP-PXZ (7 nm), film 2: substrate/TCTA : 3 wt% Ir(dmppr-mp)₂(divm) (8 nm)/CP-BP-PXZ (7 nm), film 3: substrate/TCTA (2 nm)/TPB-AC (10 nm), film 4: substrate/CP-BP-PXZ (7 nm)/TCTA (2 nm)/TPB-AC (10 nm).